Ivo W Rangelow

List of Publications by Year
in descending order

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161 papers	2,787 citations	185998 28 h-index	233125 45 g-index
161 all docs	161 docs citations	161 times ranked	2165 citing authors

#	Article	IF	Citations
1	Components for high speed atomic force microscopy. Ultramicroscopy, 2006, 106, 881-887.	0.8	220
2	Critical tasks in high aspect ratio silicon dry etching for microelectromechanical systems. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2003, 21, 1550-1562.	0.9	167
3	Piezoresistive sensors for scanning probe microscopy. Ultramicroscopy, 2000, 82, 39-48.	0.8	104
4	Nanoscale Engineering and Optical Addressing of Single Spins in Diamond. Small, 2010, 6, 2117-2121.	5.2	100
5	Hierarchical interconnections in the nano-composite material bone: Fibrillar cross-links resist fracture on several length scales. Composites Science and Technology, 2006, 66, 1205-1211.	3.8	66
6	Towards the implanting of ions and positioning of nanoparticles with nm spatial resolution. Applied Physics A: Materials Science and Processing, 2008, 91, 567-571.	1.1	64
7	Concept of deterministic single ion doping with sub-nm spatial resolution. Applied Physics A: Materials Science and Processing, 2006, 83, 321-327.	1.1	59
8	Dry etching with gas chopping without rippled sidewalls. Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena, 1999, 17, 2768.	1.6	56
9	Dry etching-based silicon micro-machining for MEMS. Vacuum, 2001, 62, 279-291.	1.6	54
10	Review of scanning probe micromachining and its applications within nanoscience. Microelectronic Engineering, 2014, 126, 191-203.	1.1	53
11	Nanolithography by scanning probes on calixarene molecular glass resist using mix-and-match lithography. Journal of Micro/ Nanolithography, MEMS, and MOEMS, 2013, 12, 031111.	1.0	49
12	Thermally driven microgripper as a tool for micro assembly. Microelectronic Engineering, 2006, 83, 1393-1395.	1.1	44
13	Piezoresistive and self-actuated 128-cantilever arrays for nanotechnology applications. Microelectronic Engineering, 2007, 84, 1260-1264.	1.1	44
14	Review Article: Active scanning probes: A versatile toolkit for fast imaging and emerging nanofabrication. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2017, 35, .	0.6	44
15	Integration of Scanning Probes and Ion Beams. Nano Letters, 2005, 5, 1087-1091.	4.5	43
16	Use of self-actuating and self-sensing cantilevers for imaging biological samples in fluid. Nanotechnology, 2009, 20, 434003.	1.3	40
17	Quantum size aspects of the piezoresistive effect in ultra thin piezoresistors. Ultramicroscopy, 2003, 97, 377-384.	0.8	39
18	Charging effect simulation model used in simulations of plasma etching of silicon. Journal of Applied Physics, 2012, 112, .	1.1	38

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19	Pattern-generation and pattern-transfer for single-digit nano devices. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2016, 34, .	0.6	34
20	Scanning probes in nanostructure fabrication. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2014, 32, .	0.6	33
21	Scanning proximal probe lithography for sub-10 nm resolution on calix[4]resorcinarene. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2011, 29, .	0.6	32
22	Scanning probe nanolithography on calixarene. Microelectronic Engineering, 2012, 97, 96-99.	1.1	32
23	Calibration and examination of piezoresistive Wheatstone bridge cantilevers for scanning probe microscopy. Ultramicroscopy, 2003, 97, 385-389.	0.8	30
24	The spring constant calibration of the piezoresistive cantilever based biosensor. Sensors and Actuators B: Chemical, 2012, 170, 201-206.	4.0	30
25	Scanning proximity probes for nanoscience and nanofabrication. Microelectronic Engineering, 2006, 83, 1449-1455.	1.1	29
26	Advanced electric-field scanning probe lithography on molecular resist using active cantilever. Journal of Micro/ Nanolithography, MEMS, and MOEMS, 2015, 14, 031202.	1.0	29
27	Atomic layer etching of SiO‹sub›2‹/sub› with Ar and CHF‹sub›3‹/sub› plasmas: A selfâ€limiting process for aspect ratio independent etching. Plasma Processes and Polymers, 2019, 16, 1900051.	1.6	29
28	<title>Fabrication of piezoresistive-sensed AFM cantilever probe with integrated tip</title>. Proceedings of SPIE, 1996, , .	0.8	28
29	DMCMN: In Depth Characterization and Control of AFM Cantilevers With Integrated Sensing and Actuation. Journal of Dynamic Systems, Measurement and Control, Transactions of the ASME, 2009, 131, .	0.9	28
30	Adaptive AFM scan speed control for high aspect ratio fast structure tracking. Review of Scientific Instruments, 2014, 85, 103706.	0.6	27
31	Large area fast-AFM scanning with active â€œQuattroâ€•cantilever arrays. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2016, 34, .	0.6	27
32	Room-temperature single dopant atom quantum dot transistors in silicon, formed by field-emission scanning probe lithography. Journal of Applied Physics, 2018, 124, .	1.1	27
33	Field emission from diamond nanotips for scanning probe lithography. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2018, 36, .	0.6	26
34	Nanoprobe maskless lithography. Proceedings of SPIE, 2010, , .	0.8	25
35	Microthermomechanical infrared sensors. Opto-electronics Review, 2014, 22, 1-15.	2.4	25
36	Profile simulation model for sub-50â€‰nm cryogenic etching of silicon using SF6/O2 inductively coupled plasma. Journal of Applied Physics, 2015, 118, .	1.1	23

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37	Duo-action electro thermal micro gripper. Microelectronic Engineering, 2007, 84, 1329-1332.	1.1	22
38	Thermo-mechanical transduction suitable for high-speed scanning probe imaging and lithography. Microelectronic Engineering, 2016, 154, 1-7.	1.1	22
39	Atomic force microscope integrated with a scanning electron microscope for correlative nanofabrication and microscopy. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2018, 36, .	0.6	22
40	The influence of reactant transport on the profiles of gas chopping etching processes: a simulation approach. Microelectronic Engineering, 2003, 67-68, 338-348.	1.1	20
41	Micromachined self-actuated piezoresistive cantilever for high speed SPM. Microelectronic Engineering, 2012, 97, 265-268.	1.1	20
42	Increased imaging speed and force sensitivity for bio-applications with small cantilevers using a conventional AFM setup. Micron, 2012, 43, 1399-1407.	1.1	19
43	Atomic layer deposition for spacer defined double patterning of sub-10 nm titanium dioxide features. Nanotechnology, 2018, 29, 405302.	1.3	19
44	High speed quasi-monolithic silicon/piezostack SPM scanning stage. Microelectronic Engineering, 2012, 98, 520-523.	1.1	18
45	Multi-eigenmode control for high material contrast in bimodal and higher harmonic atomic force microscopy. Nanotechnology, 2015, 26, 235706.	1.3	18
46	Six-axis AFM in SEM with self-sensing and self-transduced cantilever for high speed analysis and nanolithography. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2016, 34, .	0.6	17
47	Scanning probe lithography on calixarene towards single-digit nanometer fabrication. International Journal of Extreme Manufacturing, 2020, 2, 032005.	6.3	17
48	‹title›High-resolution tri-level process by downstream-microwave rf-biased etching‹/title›. , 1991, , .		16
49	Thermally driven piezoresistive cantilevers for shear-force microscopy. Microelectronic Engineering, 2009, 86, 1212-1215.	1.1	16
50	Micromachined scanning proximal probes with integrated piezoresistive readout and bimetal actuator for high eigenmode operation. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2010, 28, C6N12-C6N17.	0.6	16
51	Fast atomic force microscopy with self-transduced, self-sensing cantilever. Journal of Micro/ Nanolithography, MEMS, and MOEMS, 2015, 14, 031209.	1.0	16
52	Local formation of nitrogen-vacancy centers in diamond by swift heavy ions. Journal of Applied Physics, 2014, 116, .	1.1	15
53	Profile evolution of Cr masked features undergoing HBr-inductively coupled plasma etching for use in 25â€‚nm silicon nanoimprint templates. Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena, 2005, 23, 2073.	1.6	14
54	Quantitative force and mass measurements using the cantilever with integrated actuator and deflection detector. Microelectronic Engineering, 2009, 86, 1043-1045.	1.1	14

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55	0.1-nanometer resolution positioning stage for sub-10 nm scanning probe lithography. Proceedings of SPIE, 2013, , .	0.8	14
56	Strategies for integration of donor electron spin qubits in silicon. Microelectronic Engineering, 2006, 83, 1814-1817.	1.1	13
57	Controllable off-plane deflection of cantilevers for multiple scanning proximity probe arrays. Applied Physics A: Materials Science and Processing, 2008, 92, 525-530.	1.1	13
58	Development and modeling of an electrothermally MEMS microactuator with an integrated microgripper. Journal of Micromechanics and Microengineering, 2011, 21, 125026.	1.5	13
59	Scanning probe lithography approach for beyond CMOS devices. Proceedings of SPIE, 2013, , .	0.8	13
60	Tip Motionâ€"Sensor Signal Relation for a Composite SPM/SPL Cantilever. Journal of Microelectromechanical Systems, 2016, 25, 78-90.	1.7	13
61	Experimental study of field emission from ultrasharp silicon, diamond, GaN, and tungsten tips in close proximity to the counter electrode. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2018, 36, .	0.6	13
62	Probe-induced resistive switching memory based on organic-inorganic lead halide perovskite materials. Organic Electronics, 2019, 69, 106-113.	1.4	13
63	Mix-and-match lithography and cryogenic etching for NIL template fabrication. Microelectronic Engineering, 2020, 224, 111234.	1.1	13
64	Investigation of the sorption properties of thin Geâ€"Sâ€"AgI films deposited on cantilever-based gas sensor. Applied Physics A: Materials Science and Processing, 2007, 87, 31-36.	1.1	12
65	Improved single ion implantation with scanning probe alignment. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2012, 30, .	0.6	12
66	Low-energy electron exposure of ultrathin polymer films with scanning probe lithography. Microelectronic Engineering, 2017, 177, 78-86.	1.1	12
67	Monolithic technology for silicon nanowires in high-topographyÂarchitectures. Microelectronic Engineering, 2017, 183-184, 42-47.	1.1	12
68	Nanofabrication by field-emission scanning probe lithography and cryogenic plasma etching. Microelectronic Engineering, 2018, 192, 77-82.	1.1	12
69	Electric field scanning probe lithography on molecular glass resists using self-actuating, self-sensing cantilever. Proceedings of SPIE, 2014, , .	0.8	11
70	Molecular glass resists for scanning probe lithography. Proceedings of SPIE, 2014, , .	0.8	11
71	Fabrication of self-actuated piezoresistive thermal probes. Microelectronic Engineering, 2015, 145, 32-37.	1.1	11
72	Simulation of field emission from volcano-gated tips for scanning probe lithography. Microelectronic Engineering, 2017, 177, 19-24.	1.1	11

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73	Thermomechanically and electromagnetically actuated piezoresistive cantilevers for fast-scanning probe microscopy investigations. Sensors and Actuators A: Physical, 2018, 276, 237-245.	2.0	11
74	Correlative Microscopy and Nanofabrication with AFM Integrated with SEM. Microscopy Today, 2019, 27, 24-30.	0.2	11
75	Lithographie der nÃchsten Generation: Angesichts milliardenschwerer Entwicklungskosten muss die Industrie zwischen vier lithographischen Verfahren auswÃhlen. Physik Journal, 2000, 56, 31-36.	0.1	10
76	Active Microcantilevers for High Material Contrast in Harmonic Atomic Force Microscopy. Journal of Microelectromechanical Systems, 2015, 24, 1622-1631.	1.7	10
77	Scanning probe-based high-accuracy overlay alignment concept for lithography applications. Applied Physics A: Materials Science and Processing, 2017, 123, 1.	1.1	10
78	Field-emission scanning probe lithography tool for 150â€‰mm wafer. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2018, 36, .	0.6	10
79	Towards alternative 3D nanofabrication in macroscopic working volumes. Measurement Science and Technology, 2018, 29, 114002.	1.4	10
80	Tip-based nano-manufacturing and -metrology. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2019, 37, .	0.6	10
81	Tip- and Laser-based 3D Nanofabrication in Extended Macroscopic Working Areas. Nanomanufacturing and Metrology, 2021, 4, 132-148.	1.5	10
82	Sensors for scanning probe microscopy. Applied Physics A: Materials Science and Processing, 2003, 76, 907-911.	1.1	9
83	Thermally driven multi-layer actuator for 2D cantilever arrays. Applied Physics A: Materials Science and Processing, 2011, 102, 61-68.	1.1	9
84	ViPER: simulation software for high aspect ratio plasma etching of silicon. Microsystem Technologies, 2014, 20, 1791-1796.	1.2	9
85	Advanced electric-field scanning probe lithography on molecular resist using active cantilever. Proceedings of SPIE, 2015, , .	0.8	9
86	Magnetoelectric versus thermal actuation characteristics of shear force AFM probes with piezoresistive detection. Measurement Science and Technology, 2017, 28, 034011.	1.4	9
87	Contact atomic force microscopy using piezoresistive cantilevers in load force modulation mode. Ultramicroscopy, 2018, 184, 199-208.	0.8	9
88	Lights Out! Nano-Scale Topography Imaging of Sample Surface in Opaque Liquid Environments with Coated Active Cantilever Probes. Nanomaterials, 2019, 9, 1013.	1.9	9
89	Sensitivity Improvement to Active Piezoresistive AFM Probes Using Focused Ion Beam Processing. Sensors, 2019, 19, 4429.	2.1	9
90	Advanced Scanning Probe Nanolithography Using GaN Nanowires. Nano Letters, 2021, 21, 5493-5499.	4.5	9

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91	Microemulsion Polymerization of Butyl Acrylate under Ultrasound Irradiation. Polymer Journal, 2006, 38, 264-276.	1.3	8
92	Aspect ratio dependent plasma polymer deposition of fluorocarbons. Microelectronic Engineering, 2006, 83, 1174-1177.	1.1	8
93	On Total Internal Reflection Investigation of Nanoparticles by Integrated Micro-Fluidic System. Nano Letters, 2008, 8, 375-381.	4.5	8
94	Characterization of an electro-thermal micro gripper and tip sharpening using FIB technique. Microsystem Technologies, 2010, 16, 1901-1908.	1.2	8
95	Mix & match electron beam & scanning probe lithography for high throughput sub-10 nm lithography. Proceedings of SPIE, 2013, , .	0.8	8
96	Low temperature dry etching of chromium towards control at sub-5 nm dimensions. Nanotechnology, 2016, 27, 415302.	1.3	8
97	Nano-line width control and standards using Lateral Pattern Definition technique. Microelectronic Engineering, 2006, 83, 1555-1558.	1.1	7
98	Nanoscale pattern transfer for templates, NEMS, and nano-optics. , 2007, , .		7
99	Inverse microemulsion copolymerization of butyl acrylate and acrylamide: kinetics, colloidal parameters and some model applications. Polymer International, 2007, 56, 364-370.	1.6	7
100	New method for the precise flux calculation of neutrals for arbitrary surfaces in profile etch simulations. Microelectronic Engineering, 2008, 85, 982-984.	1.1	7
101	Integrated plasma processing simulation framework, linking tool scale plasma models with 2D feature scale etch simulator. Microelectronic Engineering, 2009, 86, 976-978.	1.1	7
102	ARCH-type micro-cantilever FPA for uncooled IR detection. Microelectronic Engineering, 2012, 98, 614-618.	1.1	7
103	Tailored molecular glass resists for scanning probe lithography. Proceedings of SPIE, 2015, , .	0.8	7
104	Tip-based nanolithography methods and materials. Frontiers of Nanoscience, 2016, , 497-542.	0.3	7
105	Charged particle single nanometre manufacturing. Beilstein Journal of Nanotechnology, 2018, 9, 2855-2882.	1.5	7
106	Scanning probe lithography for electronics at the 5nm scale. SPIE Newsroom, 0, , .	0.1	7
107	Investigations of the sorption behaviour of amorphous nitrogen-rich carbon nitride films as sensitive layers for cantilever-based chemical sensors. Applied Physics A: Materials Science and Processing, 2004, 79, 531-536.	1.1	6
108	Micro-fluidic analysis based on total internal light reflection. Microelectronic Engineering, 2006, 83, 1294-1297.	1.1	6

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109	Diffraction under total internal reflection for micro-fluidic analysis. Applied Physics A: Materials Science and Processing, 2006, 84, 191-196.	1.1	6
110	Temperature and oxygen concentration effects on anisotropy in chromium hard mask etching for nanoscale fabrication. Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films, 2019, 37, .	0.9	6
111	Cryogenic etching for pattern transfer into silicon of Mix-and-Match structured resist layers. Microelectronic Engineering, 2020, 227, 111325.	1.1	6
112	Lateral force microscopy using cantilevers with integrated Wheatstone bridge piezoresistive deflection sensor. Proceedings of SPIE, 1996, , .	0.8	5
113	Microfabricated cantilever with metallic tip for electrostatic and capacitance microscopy and its application to investigation of semiconductor devices. Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena, 2004, 22, 506.	1.6	5
114	Application of a Scanning Thermal Nano-Probe for Thermal Imaging of High Frequency Active devices. Japanese Journal of Applied Physics, 2005, 44, 6823-6825.	0.8	5
115	Experimental setup for characterization of self-actuated microcantilevers with piezoresistive readout for chemical recognition of volatile substances. Review of Scientific Instruments, 2008, 79, 094101.	0.6	5
116	Self-actuated, self-sensing cantilever for fast CD measurement. Proceedings of SPIE, 2015, , .	0.8	5
117	Fabrication Process for an Optomechanical Transducer Platform with Integrated Actuation. Journal of Research of the National Institute of Standards and Technology, 2016, 121, 507.	0.4	5
118	Next generation lithographyâ€"the rise of unconventional methods?. Frontiers of Nanoscience, 2016, 11, 479-495.	0.3	5
119	Sharp GaN nanowires used as field emitter on active cantilevers for scanning probe lithography. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2018, 36, .	0.6	5
120	Theoretical investigation of the enhancement factor for a single field emitter in close proximity to the counter electrode. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2018, 36, 06JL01.	0.6	5
121	Balancing ion parameters and fluorocarbon chemical reactants for SiO2 pattern transfer control using fluorocarbon-based atomic layer etching. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2019, 37, .	0.6	5
122	Field-emission scanning probe lithography with self-actuating and self-sensing cantilevers for devices with single digit nanometer dimensions. , 2018, , .		5
123	Mechanical characterization of membrane like microelectronic components. Microelectronic Engineering, 2006, 83, 1036-1042.	1.1	4
124	Selective Laser Ablation in Resists and Block Copolymers for High Resolution Lithographic Patterning. Journal of Photopolymer Science and Technology = [Fotoporima Konwakai Shi], 2015, 28, 663-668.	0.1	4
125	High-throughput process chain for single electron transistor devices based on field-emission scanning probe lithography and Smart Nanoimprint lithography technology. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2019, 37, 021603.	0.6	4
126	Tip-based electron beam induced deposition using active cantilevers. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2019, 37, .	0.6	4

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127	Line edge roughness metrology software. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2020, 38, .	0.6	4
128	Atomic force microscope integrated into a scanning electron microscope for fabrication and metrology at the nanometer scale. , 2019, , .		4
129	Nanostructuring Techniques for 3C-SiC(100) NEMS Structures. Materials Science Forum, 2010, 645-648, 841-844.	0.3	3
130	Parallel SPM cantilever arrays for large area surface metrology and lithography. Proceedings of SPIE, 2014, , .	0.8	3
131	Estimator based multi-eigenmode control of cantilevers in multifrequency Atomic Force Microscopy. , 2015, , .		3
132	Cantilever array with optomechanical read-out and integrated actuation for simultaneous high sensitivity force detection. , 2016, , .		3
133	Nanoscale lift-off process using field emission scanning probe lithography. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2019, 37, .	0.6	3
134	Field emission scanning probe lithography with GaN nanowires on active cantilevers. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2020, 38, 032806.	0.6	3
135	Determination of the mixing ratio of aÂflowing gas mixture with self-actuated microcantilevers. Journal of Sensors and Sensor Systems, 2020, 9, 71-78.	0.6	3
136	Single nano-digit and closed-loop scanning probe lithography for manufacturing of electronic and optical nanodevices. , 2018, , .		3
137	Thermal imaging of microwave power GaAs-FET with scanning thermal nanoprobe. , 2002, , .		2
138	Radicals transport modelling in NANOJET. Applied Physics A: Materials Science and Processing, 2005, 81, 1661-1666.	1.1	2
139	Raster-Sonden-Mikroskopie mit Cantilever-Arrays (Scanning Probe Microscopy with Cantilever) Tj ETQq1 1 0.784314 rgBT /Overlock 1	0.3	2
140	Irregular film thickness distribution in C4F8 inductively coupled plasma polymer deposition. Microelectronic Engineering, 2012, 98, 524-527.	1.1	2
141	Shear force microscopy using piezoresistive cantilevers in surface metrology. , 2014, , .		2
142	Heterodyne standing-wave interferometer / Heterodynes Stehende-Welle-Interferometer. TM Technisches Messen, 2018, 85, s80-s85.	0.3	2
143	Nanostructuring of Mo/Si multilayers by means of reactive ion etching using a three-level mask. Thin Solid Films, 2004, 458, 227-232.	0.8	1
144	Chromium nano-width ribbons by standard lithography and wet etching. Microelectronic Engineering, 2004, 73-74, 588-593.	1.1	1

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145	Low Frequency Measurements Using Piezoresistive Cantilever MEMS Devices â€“ The Problem of Thermal Drift. Procedia Engineering, 2014, 87, 1259-1262.	1.2	1
146	Single mask fabrication process for movable MEMS devices. Microsystem Technologies, 2014, 20, 955-961.	1.2	1
147	Simulation of Fowler-Nordheim emission for scanning probe lithography. , 2017, , .		1
148	Polymerâ€“metal coating for high contrast SEM cross sections at the deep nanoscale. Nanoscale, 2018, 10, 22884-22895.	2.8	1
149	Silk as a biodegradable resist for field-emission scanning probe lithography. Nanotechnology, 2020, 31, 435303.	1.3	1
150	Parallel active cantilever AFM tool for high-throughput inspection and metrology. , 2019, , .		1
151	High throughput AFM inspection system with parallel active cantilevers. , 2019, , .		1
152	Mask-less nano-structuring of hydrogen terminated diamond using localized field emission scanning probe lithography (FE-SPL). Applied Physics Letters, 2022, 120, 093503.	1.5	1
153	Refractometric investigation and analysis of nano-scaled dispersions. , 2005, 5830, 491.		0
154	Imaging Cellular and Viral Materials with Small Cantilevers Developed for High Speed Atomic Force Microscopy. Materials Research Society Symposia Proceedings, 2007, 1025, 1.	0.1	0
155	Design and Fabrication of a Horizontal Thermal Micro-Actuator with Integrated Micro Tweezers. Advances in Science and Technology, 2008, 54, 378-383.	0.2	0
156	Thermographischer Detektor basierend auf einem neuartigen Mikro-Spiegel Sensor. TM Technisches Messen, 2014, 81, 219-227.	0.3	0
157	Control of first and higher transverse eigenmodes of active Atomic Force Microscope cantilevers. , 2016, , .		0
158	An Integrated in SEM Multi-Purpose AFM Instrument Utilizing an Active Cantilever. Microscopy and Microanalysis, 2019, 25, 806-807.	0.2	0
159	Active Cantilevers with Diamond-Tip for Field Emission Scanning Probe Lithography and Imaging. , 2019, , .		0
160	Fabrication of optical nanodevices through field-emission scanning probe lithography and cryogenic etching. , 2018, , .		0
161	Micro- and nanofabrication technologies using the nanopositioning and nanomeasuring machines. , 2019, , .		0